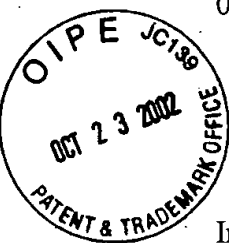


03500.015382.

PATENT APPLICATION



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
 :
 TAKAHARU KONDO ET AL.)
 :
 Application No.: 09/866,665)
 :
 Filed: May 30, 2001)
 :
 For: SILICON-TYPE THIN)
 FILM FORMATION)
 PROCESS, SILICON TYPE)
 THIN FILM, AND)
 PHOTOVOLTAIC DEVICE)

Examiner: Brian L. Mutschler

Group Art Unit: 1753

October 22, 2002

7/A
W.M.
10/30/02

Commissioner for Patents
Washington, D.C. 20231

RECEIVED
OCT 25 2002
TC 1100

AMENDMENT AND PETITION FOR EXTENSION OF TIME

Sir:

Applicants petition to extend the time for response to the Office Action dated May 9, 2002 to November 9, 2002. A check in the amount of \$920.00 for payment of the extension fee is enclosed. Please charge any additional fee required for the extension, and credit any overpayment, to Deposit Account 06-1205.

In response to the Office Action dated May 9, 2002, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Please replace the Abstract of the Disclosure with the substitute Abstract of the Disclosure as follows:

10/24/2002 SSESHE1 00000074 09866665 920.00 0P
01 FC:1253